

Recitation 8: MOS Electrostatics under Bias & MOS Capacitor

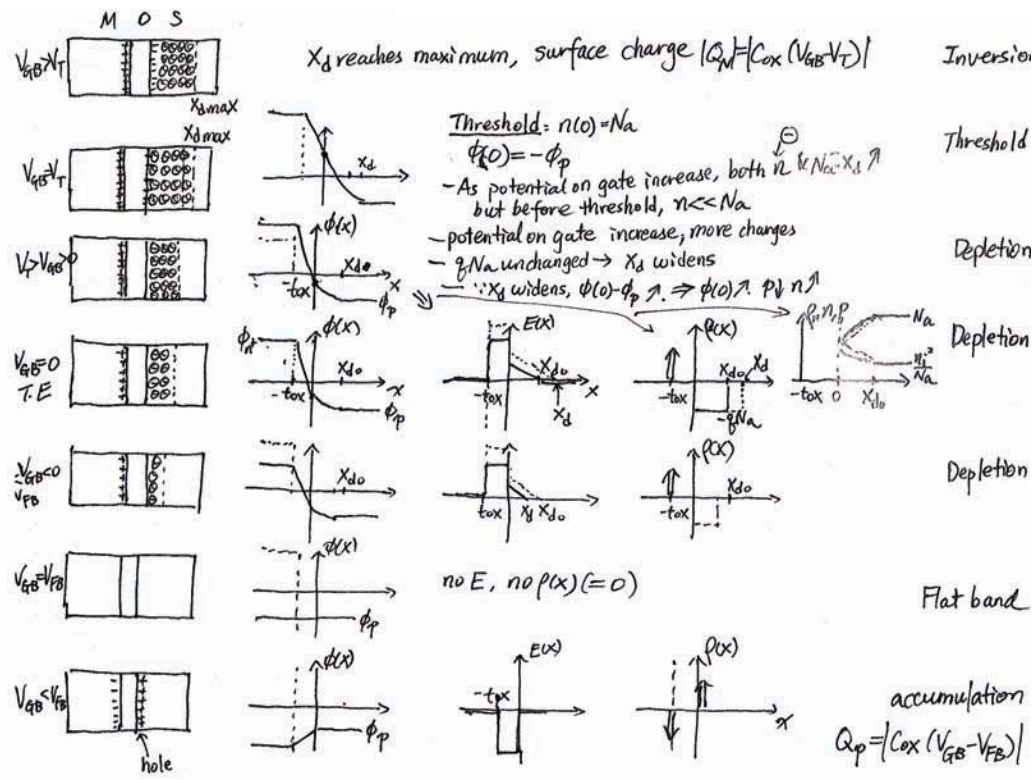
Yesterday we learned a lot of new “names”: (terminologies)

- Depletion (regime)
- Flat Band
- Accumulation (regime)
- Threshold
- Inversion (regime)

These are terminologies to describe electrostatics conditions of MOS structure under bias.

MOS Electrostatics under Bias

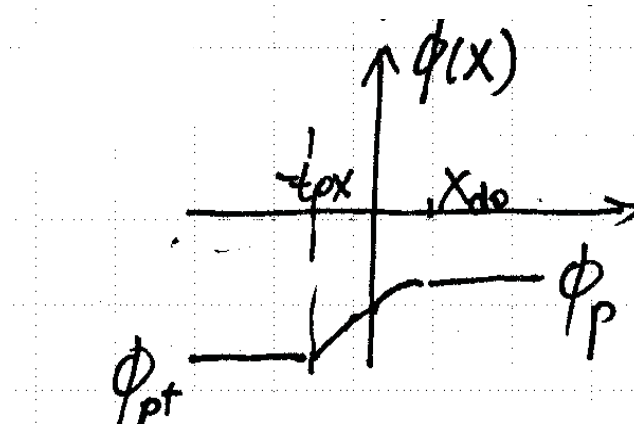
As an exercise, let us consider a situation where we have n^+ gate and p-type substrate.



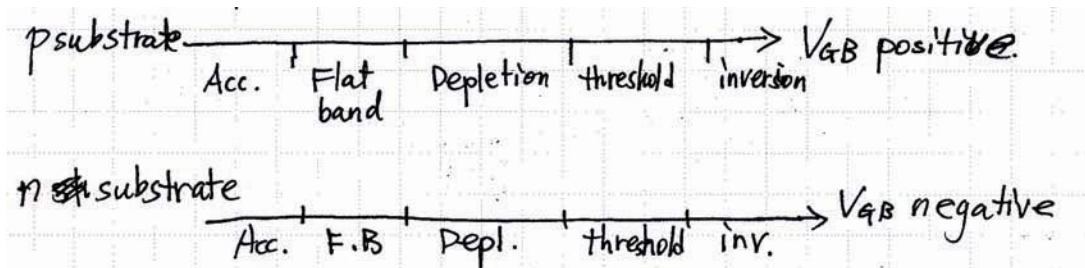
Note:

1. Surface charge
2. What about a p^+ gate, p-substrate MOS structure?

Under T.E.,



So it does not depend on what gate



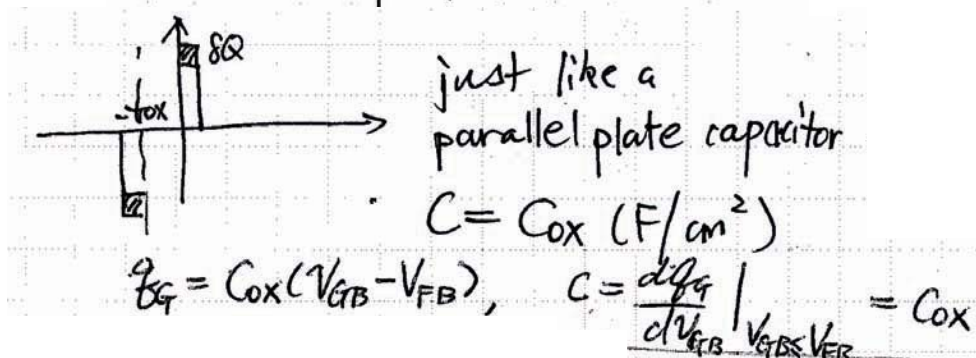
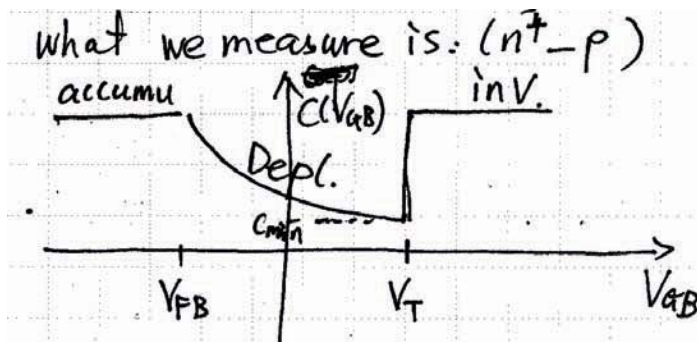
3. V_{FB} always = $-(\phi_{gate} - \phi_{body})$

MOS Capacitor

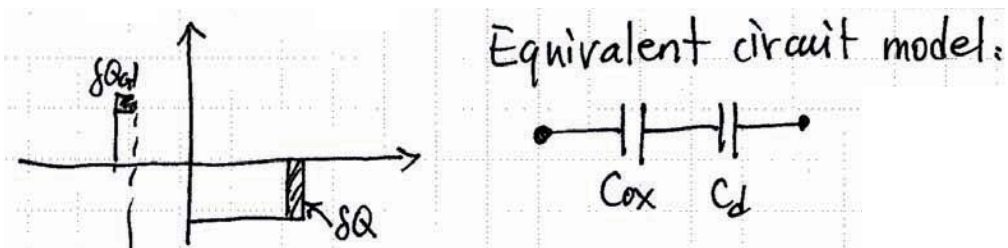
Now let us look at the capacitances of the MOS structure under these regimes:

$$C = \left. \frac{dq_G}{dV_{GB}} \right|_{V_{GB}}$$

1. Accumulation: → Flat band



2. Depletion Regime:

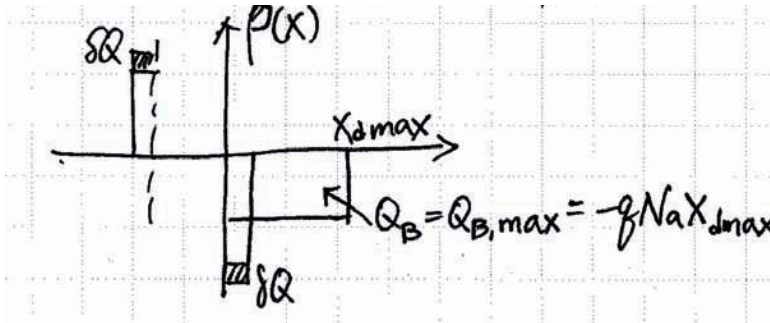


$$\begin{aligned}
 q_G &= q \cdot N_a \cdot x_d(V_{GB}) \\
 &= \frac{qN_a\epsilon_s}{C_{ox}} \left(\sqrt{1 + \frac{2C_{ox}^2(V_{GB} - V_{FB})}{q\epsilon_s N_a}} - 1 \right) \\
 \frac{1}{C_{tot}} &= \frac{1}{C_{ox}} + \frac{1}{C_d} \\
 C_{ox} &= \frac{\epsilon_{ox}}{t_{ox}} \\
 C_d &= \frac{\epsilon_s}{x_d}
 \end{aligned}$$

As V_{GB} continues increasing, $x_d \uparrow$, $C_d \downarrow$, $C_{tot} \downarrow$ until x_d reaches $x_{d,max}$ when $V_{GB} = V_T$:

$$x_{d,max} = \sqrt{\frac{2\epsilon_s(-2\phi_p)}{qN_a}} \quad \& \quad C_{min} = \frac{\epsilon_s}{x_{d,max}}$$

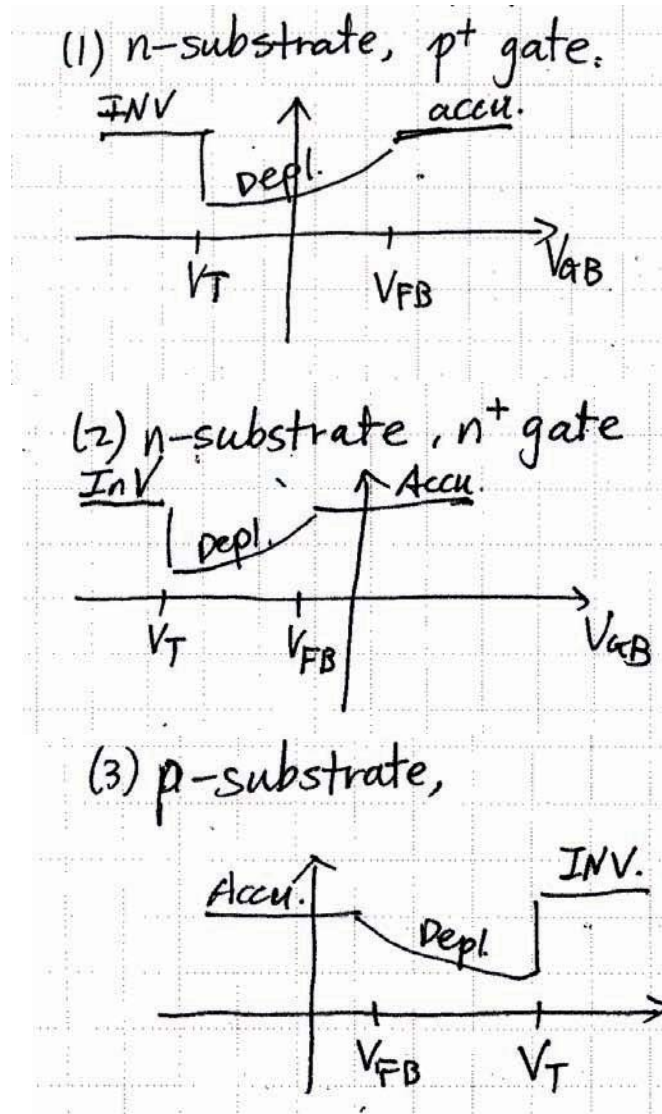
3. Inversion: $V_{GB} > V_T$, $x_d = x_{d,max}$



$C = C_{ox}$ again:

$$\begin{aligned}
 C &= \frac{d}{dV_{GB}} [C_{ox}(|V_{GB} - V_T|) + |Q_{B,max}|] \Big|_{V_{GB}} \\
 C &= C_{ox} \quad \text{because } Q_{B,max} \text{ does not change}
 \end{aligned}$$

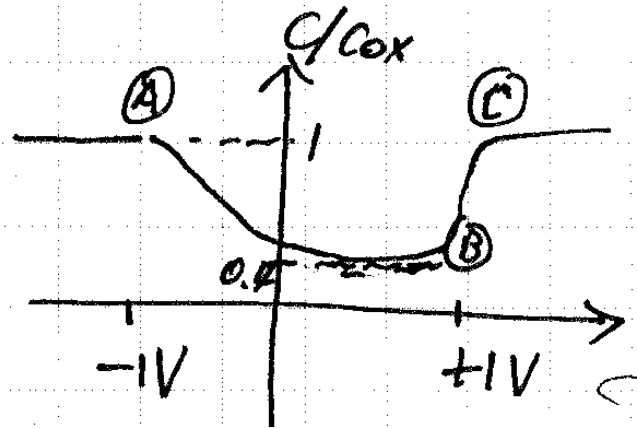
Note: This is a very powerful technique to tell a lot of information of the wafer, doping, type of devices!



Exercise

From textbook pg. 168-170: n^+ poly gate, $\phi_{n^+} = 550 \text{ mV}$.

1. Substrate doping type? Does **A** or **C** correspond to V_{FB} ?



$$V_{FB} = -1 \text{ V}, V_T = 1 \text{ V}$$

$$V_{FB} = -1 \text{ V} = -(0.55 \text{ V} - \phi_{\text{body}})$$

$$\Rightarrow \phi_{\text{body}} = -0.45 \text{ V}$$

$$\Rightarrow \text{p type substrate, } \phi_p = -60 \text{ mV} \cdot \log \frac{N_a}{n_i} = -450 \text{ mV}$$

$$\text{or } N_a = 3.2 \times 10^{17} \text{ cm}^{-3}$$

2. Find t_{ox} :

$$\frac{C_{\min}}{C_{\text{ox}}} = \frac{C(V_{GB} = V_T)}{C_{\text{ox}}} = \frac{1}{\sqrt{1 + \frac{2C_{\text{ox}}^2(V_T - V_{GB})}{q\epsilon_s N_a}}} = 0.4$$

$V_T = 1 \text{ V}, V_{FB} = -1 \text{ V}$, solve for C_{ox} :

$$C_{\text{ox}} = 2.55 \times 10^{-7} \text{ F/cm}^2$$

$$C_{\text{ox}} = \frac{\epsilon_{\text{ox}}}{t_{\text{ox}}} = \sqrt{\frac{q\epsilon_s N_a}{2(V_T - V_{FB})} \left[\left(\frac{C_{\text{ox}}}{C_{\min}} \right)^2 - 1 \right]}$$

$$t_{\text{ox}} = 132 \text{ \AA}$$

or we can use $V_T = V_{FB} - 2\phi_B + \frac{1}{C_{\text{ox}}} \sqrt{\epsilon_s q N_a (-2\phi_B)}$ to calculate C_{ox}

3. Find the gate charge Q_G for $V_{GB} = -3\text{ V}$ and $V_{GB} = 3\text{ V}$.

- $V_{GB} = -3\text{ V}$ corresponds to accumulation:

$$\begin{aligned} Q_G = Q_p &= C_{\text{ox}}(V_{GB} - V_{\text{FB}}) \\ &= C_{\text{ox}}(-3 - (-1)) = C_{\text{ox}} \cdot (-2\text{ V}) \\ &= -5.1 \times 10^{-7} \text{ C/cm}^2 \quad \text{charge on gate is negative} \end{aligned}$$

- $V_{GB} = 3\text{ V}$ corresponds to inversion:

$$\begin{aligned} Q_G &= |Q_N| + |Q_{B,\text{max}}| = Q_N \\ &= C_{\text{ox}}(V_{GB} - V_T) = C_{\text{ox}}(3 - 1) = 5.1 \times 10^{-7}, \text{ C/cm}^2 \\ |Q_{B,\text{max}}| &= qN_a x_{\text{dmax}} = \sqrt{2q\epsilon_s N_a (-2\phi_p)} \\ &= \sqrt{2 \times 1.6 \times 10^{-19} \times 11.9 \times 8.85 \times 10^{-14} \times 3.2 \times 10^{17} \times 2 \times 0.45} \\ &= 2.8 \times 10^{-7} \text{ C/cm}^2 \\ Q_G &= 5.1 \times 10^{-7} \text{ C/cm}^2 + 2.8 \times 10^{-7} \text{ C/cm}^2 \\ &= 7.9 \times 10^{-7} \text{ C/cm}^2 \end{aligned}$$

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6.012 Microelectronic Devices and Circuits
Spring 2009

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